

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	14620	(wafer or substrate or semiconductor) near4 (photograph\$4 or picture\$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/08 11:10
S2	578	(wafer or substrate or semiconductor) near4 (photograph\$4 or picture\$4) same ((pattern\$4 or imag\$4) near3 (data or information))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/08 11:11
S3	116	S2 and (\$4lithograph\$4 or exposure) and (reticle or mask)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/08 11:12
S4	51	S3 and (((detect\$4 or calculat\$4 or measur\$4 or sens\$4 or obtain\$4) near4 (aberration or deviation or error or offset) same ((pattern\$4 or imag\$4 or feature or shape)))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/08 11:20
S5	84	S3 and (display\$4 or monitor)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/08 11:26
S6	69	S3 and ((imag\$4 or pattern\$4) adj2 signal)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/08 11:29
S7	56	S2 and ("355"/\$.ccls. or "250"/\$.ccls. or "430"/\$.ccls.)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/08 13:29
S8	12280	(detect\$4 or measur\$4 or photograph\$4 or sens\$4) near4 (defect or error or deviation or offset) near5 (substrate or wafer or semiconductor)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/08 13:28
S9	2023	S8 and ("355"/\$.ccls. or "250"/\$.ccls. or "430"/\$.ccls.)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/08 13:29

## EAST Search History

S10	96	S9 and arbitrary near4 (pattern\$4 or imag\$4)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/08 13:45
S11	2	"6775815".pn.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/08 13:41